

LISTING OF THE CLAIMS

This listing of claims will replace all prior versions, and listings, of claims in the application:

Claim 1 (Currently Amended)

A substrate treating apparatus for treating substrates, comprising:

a treating tank for receiving and treating the substrates;

holding means movable, while holding the substrates in a cantilever mode, between a treating position in said treating tank and a transfer position above said treating tank;

transport means for supporting the substrates and transferring the substrates to and from said holding means in said transfer position;

detecting means for detecting a posture variation of said holding means; and

correcting means for correcting a position of one of said holding means and said transport means;

wherein said correcting means performs a correction according to the posture variation of said holding means detected by said detecting means in time of transfer of the substrates between said holding means and said transport means;

wherein said correcting means includes support means for supporting said holding means to be rockable about a cantilever point of said holding means, and drive means for rocking said holding means about said cantilever point;

a through hole formed in a cantilever proximal portion of said holding means;

a rigid member inserted into said through hole; and

positioning means for moving said holding means, by using said rigid member, in an opposite direction to a direction of movement of said cantilever point of said holding means.

Claims 2-3 (Canceled)

Claim 4 (Original)

A substrate treating apparatus as defined in claim 1, wherein said detecting means includes a laser displacement gauge or image processing means for performing a detection from a position spaced from said holding means.

Claims 5-6 (Canceled)

Claim 7 (Original)

A substrate treating apparatus as defined in claim 1, wherein said detecting means is mounted in a proximal portion of said holding means.

Claims 8-9 (Canceled)

Claim 10 (Original)

A substrate treating apparatus as defined in claim 4, wherein said detecting means is mounted in a proximal portion of said holding means.

Claim 11 (Original)

A substrate treating apparatus as defined in claim 7, wherein said detecting means is arranged to detect an angular acceleration or a distortion.

Claim 12 (Original)

A substrate treating apparatus as defined in claim 1, wherein said detecting means includes contact type detecting means for performing a detection while in contact with said holding means.

Claim 13 (Canceled)

Claim 14 Original)

A substrate treating apparatus as defined in claim 1, wherein said correcting means performs a correction based on a posture of said holding device unloaded with the substrates.

Claim 15 (Canceled)

Claim 16 (Original)

A substrate treating apparatus as defined in claim 1, wherein said correcting means performs a correction successively while said holding device shifts between an unloaded state and a substrate holding state.

Claim 17 (Original)

A substrate treating apparatus as defined in claim 1, wherein said correcting means includes advance/retreat drive means for advancing and retreating said support means along a substrate supporting side.

Claim 18 (Currently Amended)

A substrate treating apparatus as defined in claim 1 2, wherein said drive means includes a cam.

Claim 19 (Currently Amended)

A substrate treating apparatus as defined in claim 1 2, wherein said drive means includes a piezoelectric element.

Claim 20 (Currently Amended)

A substrate treating apparatus as defined in claim 1 2, wherein said support means includes a goniostage or a spherical seat.